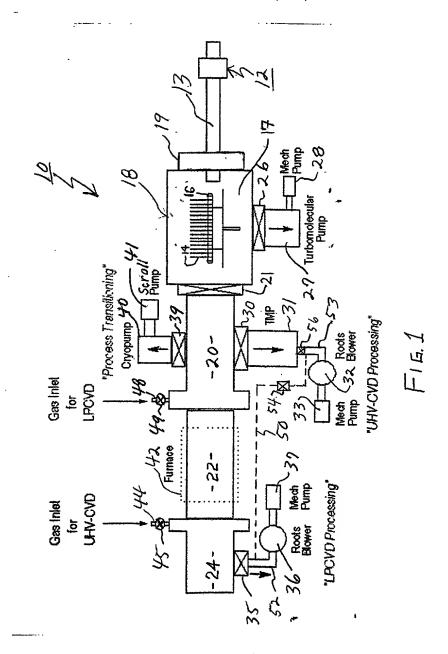
Sheet 1/3 Jack Chu et al. BUR920000077US1 (MFC)



2/3 (BUR920000077US1) "UHV-CVD Processing" "LPCVD Processing" Mech Pump Furnace Gas InLet for UHV-CVD

3/3 (BUR920000077US1)

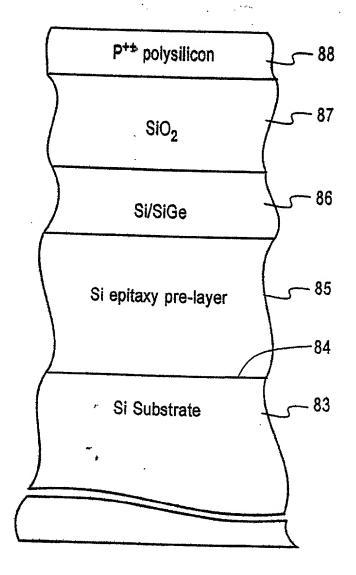


Fig. β